

**S/N 10/823,314**

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: Neo C. Peng et al.

Examiner: Samuel M Heinrich

Serial No.: 10/823,314

Group Art Unit: 1725

Filed: April 13, 2004

Docket No.: 303.772US2

Title: WAFER DICING DEVICE AND METHOD

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**AMENDMENT AND RESPONSE UNDER 37 CFR § 1.111**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

This paper responds to the Office Action mailed on January 5, 2006. Please amend the above-identified patent application as follows.

This response is accompanied by a Petition, as well as the appropriate fee, to obtain a one-month extension of the period for responding to the Office Action, thereby moving the deadline for response from April 5, 2006 to May 5, 2006.